

Institute of Radiation Physics

Radiation Source ELBE

Status report of ELBE and GaN

BETH kickoff meeting, Siegen

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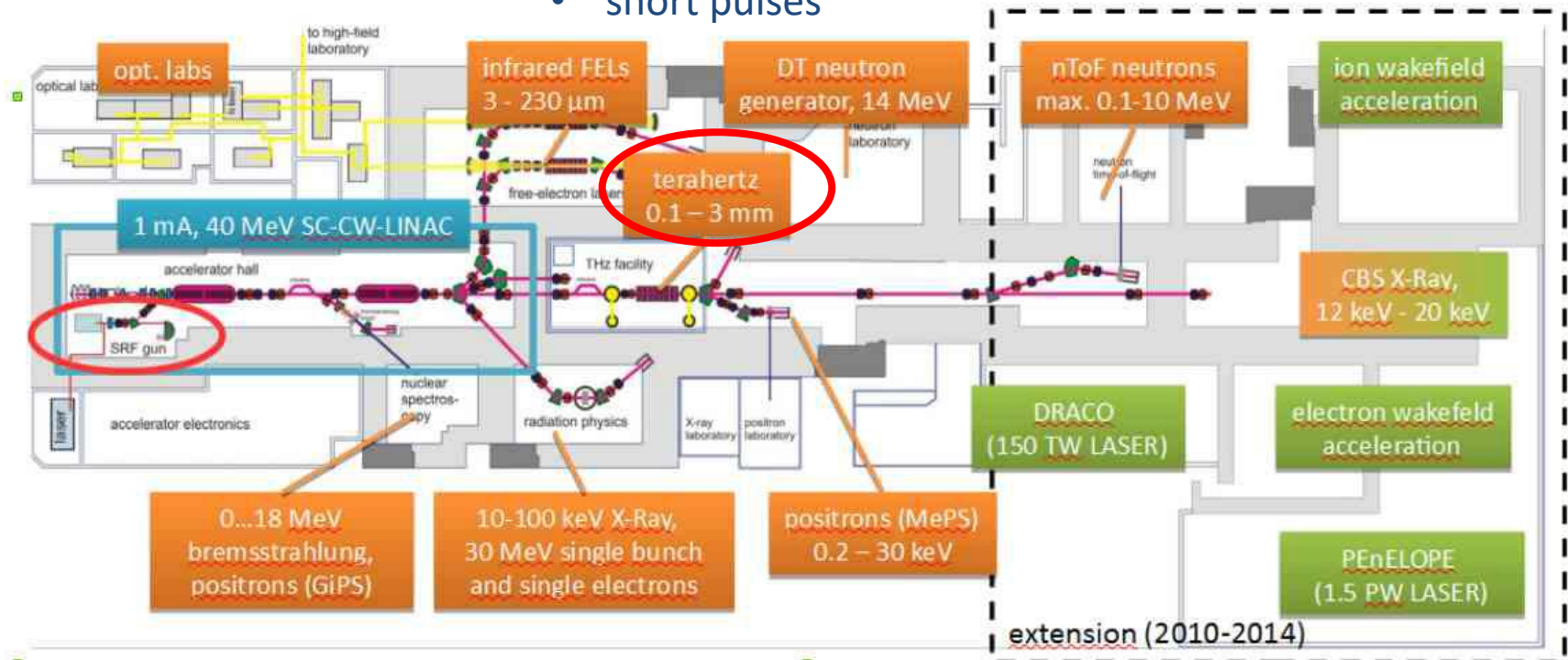
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Performance of the SRF Gun

- Advantages of SRF Gun II:
- continuous wave operation (CW)
 - higher bunch charge
 - lower transverse emittance
 - short pulses

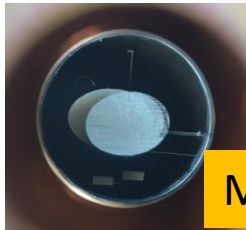
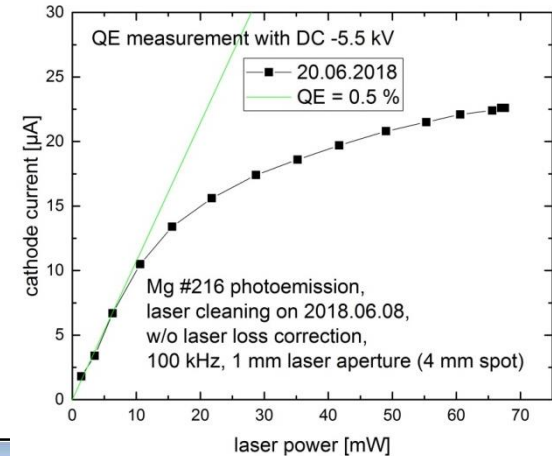


- working hours for THz radiation production at ELBE, all TELBE shifts in 2019 (101 shifts a 12 h)

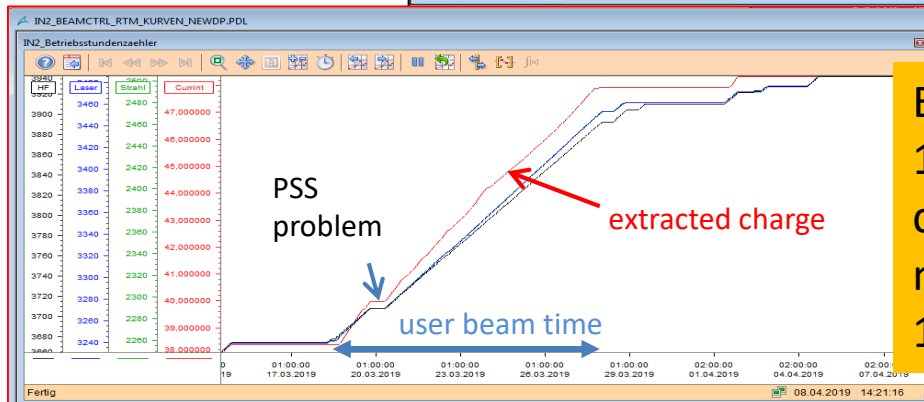
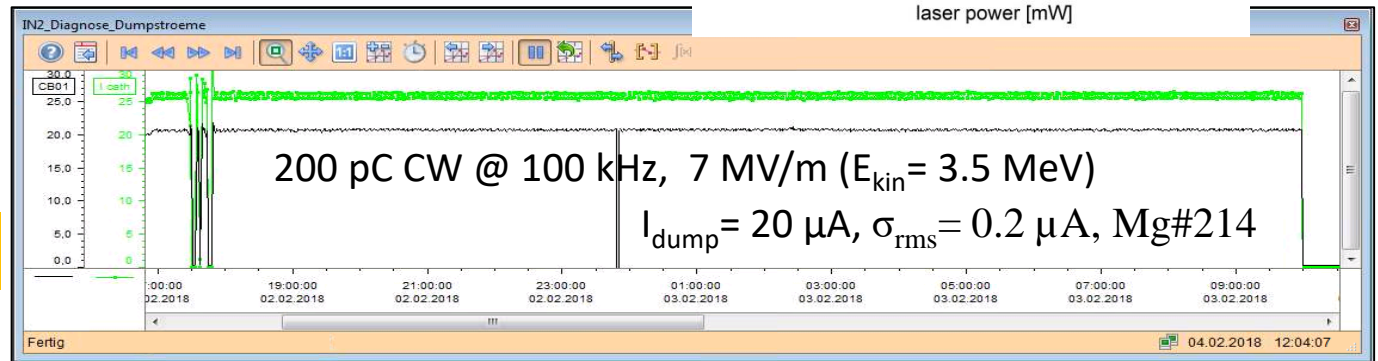
Mg Photocathode

Mg cathodes work routinely in ELBE SRF gun at HZDR

- bulk Mg plugs, polished and chem. cleaned
- UV laser cleaning (drive laser)
- best QE 0.3 % ... 0.5 %
- low risk of cavity contamination
- extremely long life time in 10^{-9} mbar vacuum
- cleaning can be several times repeated



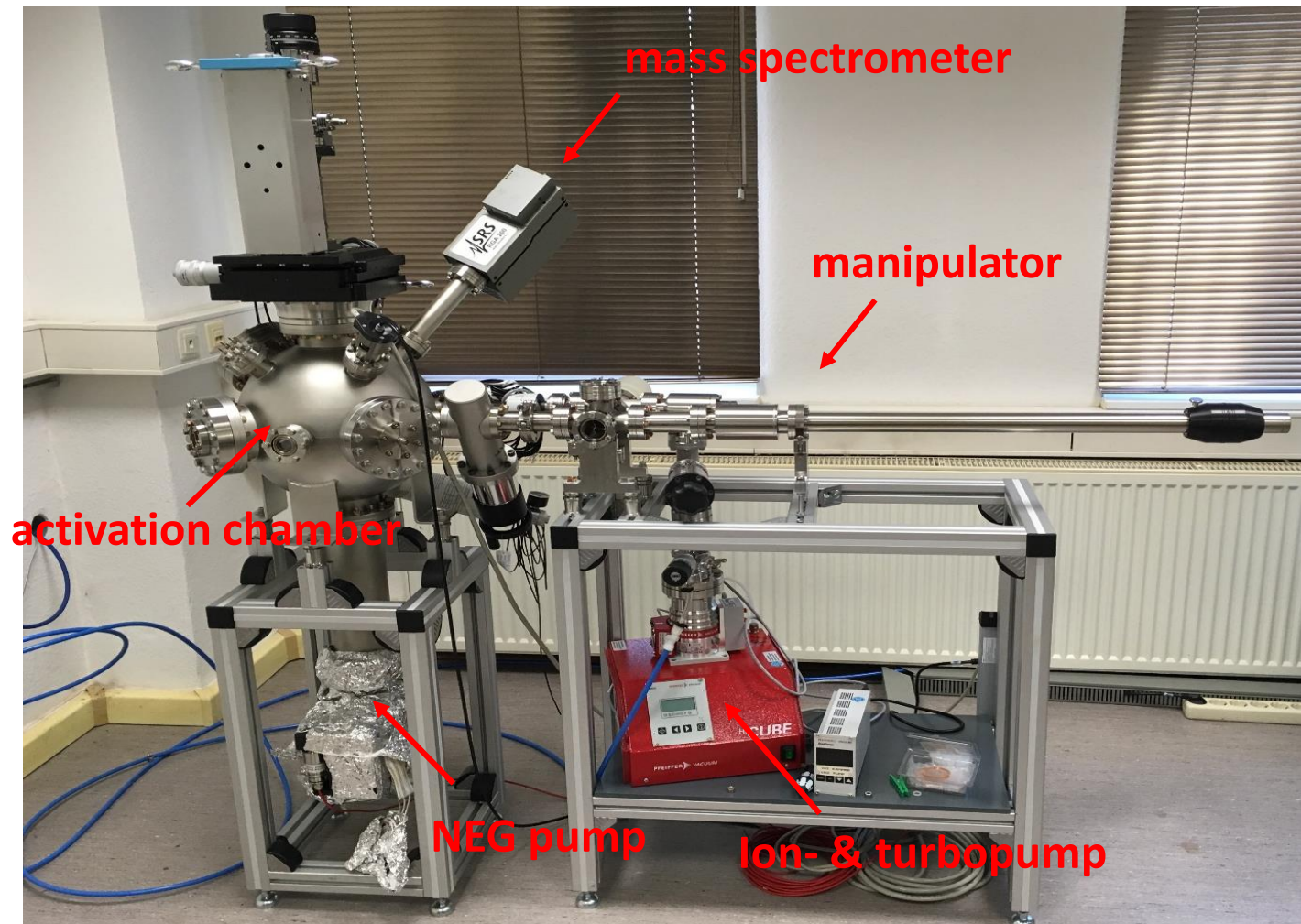
Mg #214



ELBE run spring 2019
17 x 12 h shifts for external users
ca. 200 h beam time in CW
no break due to gun problems
10 C charge extracted

GaN Photocathode Research

Build-up and commissioning of GaN chamber



GaN Photocathode Research

DAQ-GUI

File Bearbeiten Ausführen Werkzeuge Fenster Hilfe

GUI Man



Stopwatch

Start Stop

Logging

C:\Users\schab53\Desktop\Logging

Log on Log off

Comment

Save

O2-Valve

Voltage/V 0 200 400 600 0

HV OFF

Equivalent Voltage 1,63683

HV ON/OFF

Extern/Intern

Set

DELTA ELEKTRONIKA

Voltage/V 0 2,5 5 7,5 10 12,5 15 2

Current/A 0 2 4 6 8 10 1

Transferchamber

Confirm Set

Voltage Measurement Delta Elektronika

0,71



Current Measurement Delta Elektronika

1,00



Power/W 0,707912

Cathode-Anode-Voltage

Voltage/V 0 200 400 600 800 1000 100

Equivalent Voltage 100,01

Set

Cathode Current

0,00



Temperature and Pressure

Pressure

0,00



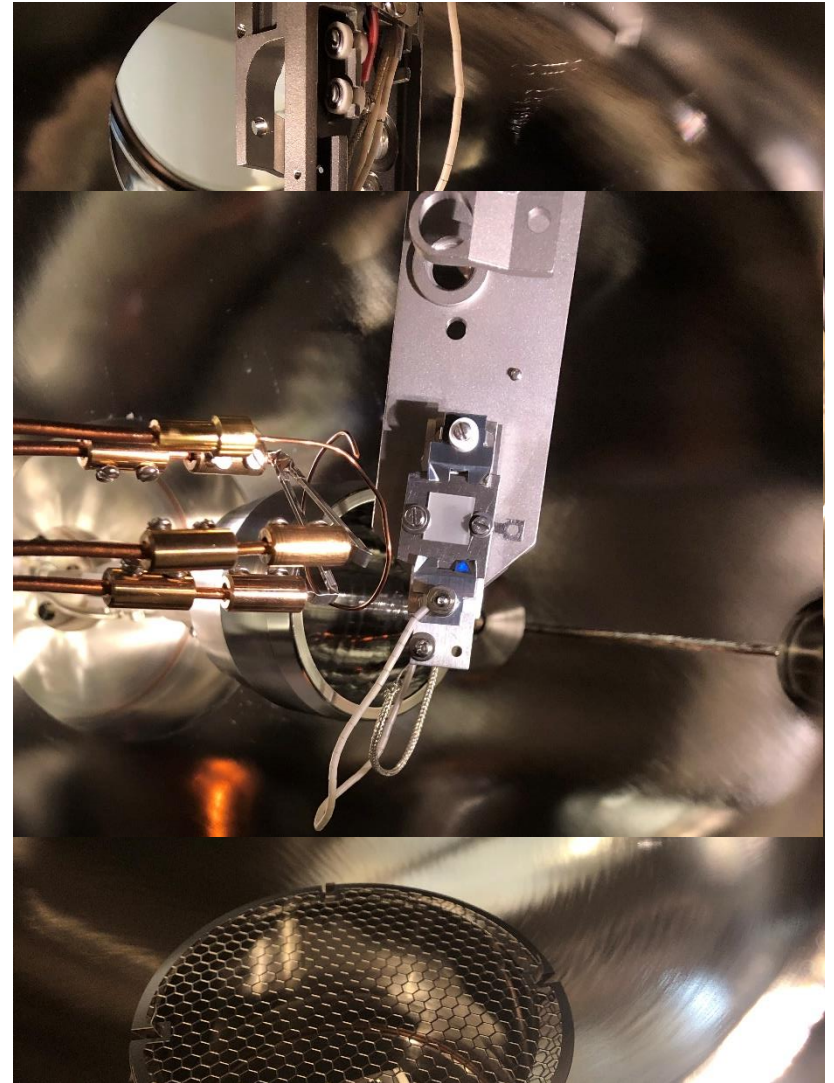
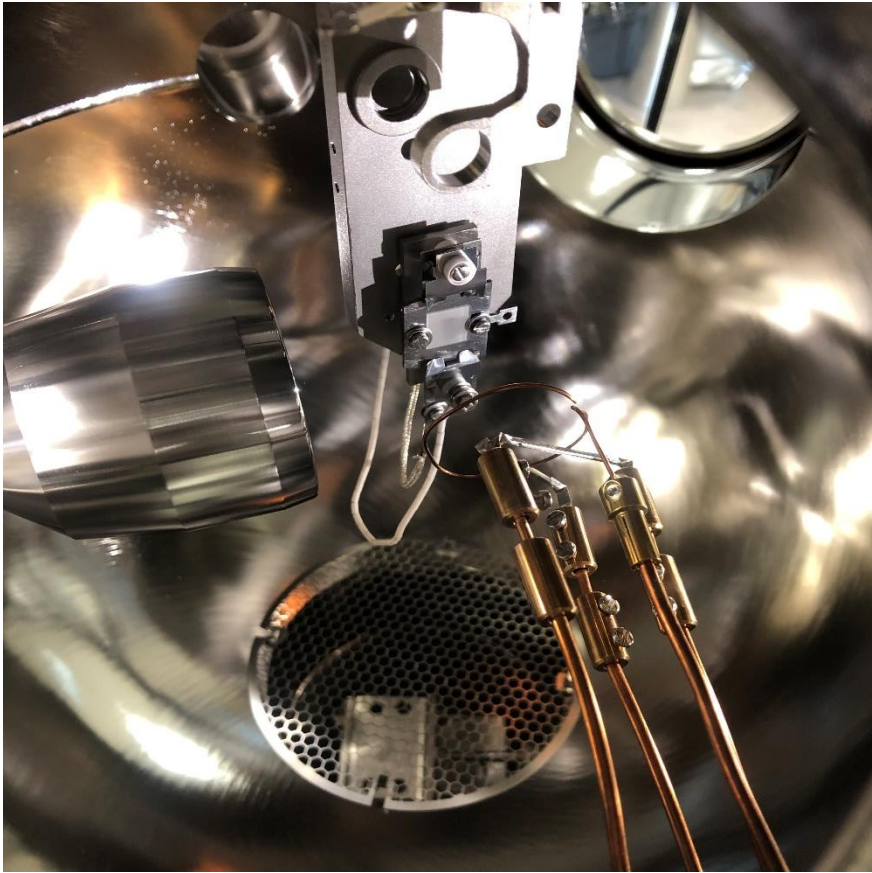
Temperature/°C Cathode 34,1627

Temperature/°C Transferchamber 30,087



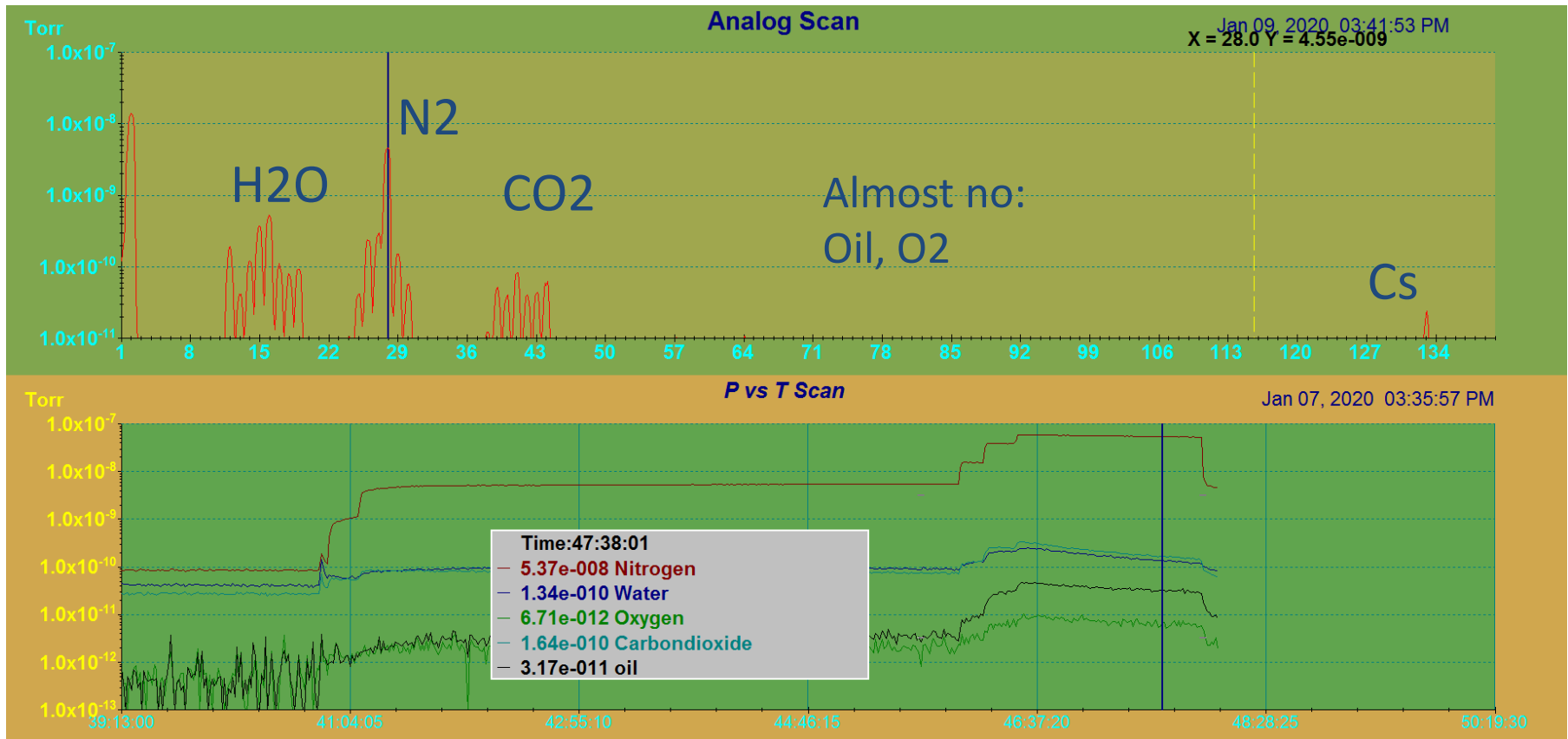
GaN Photocathode Research

Build-up and commissioning of GaN chamber



GaN Photocathode Research

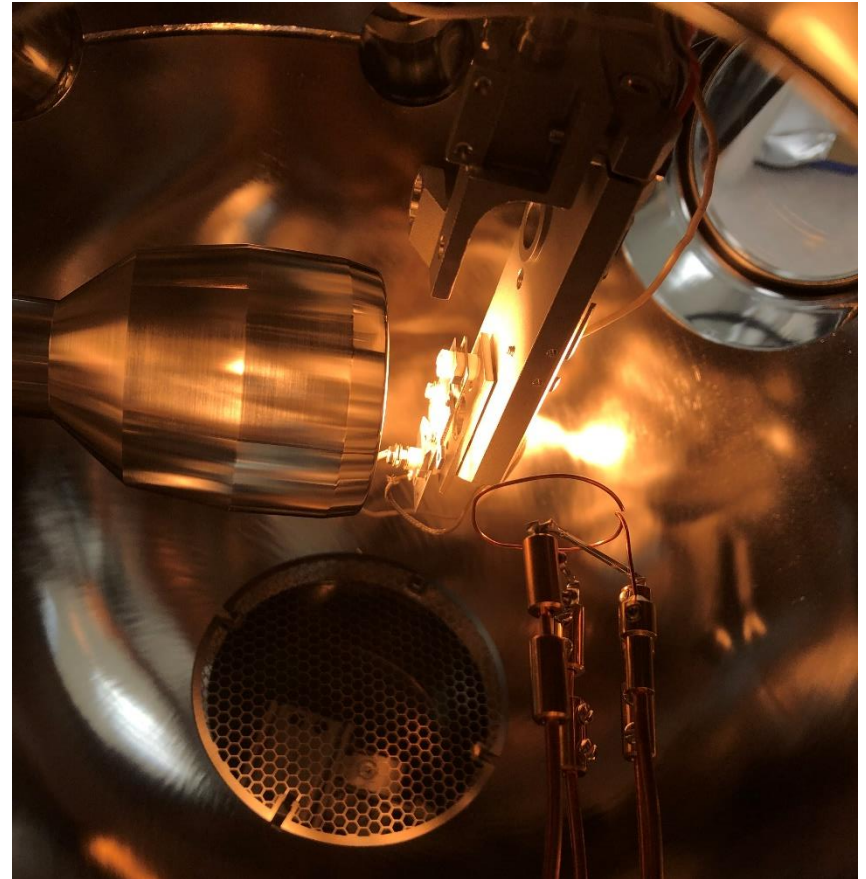
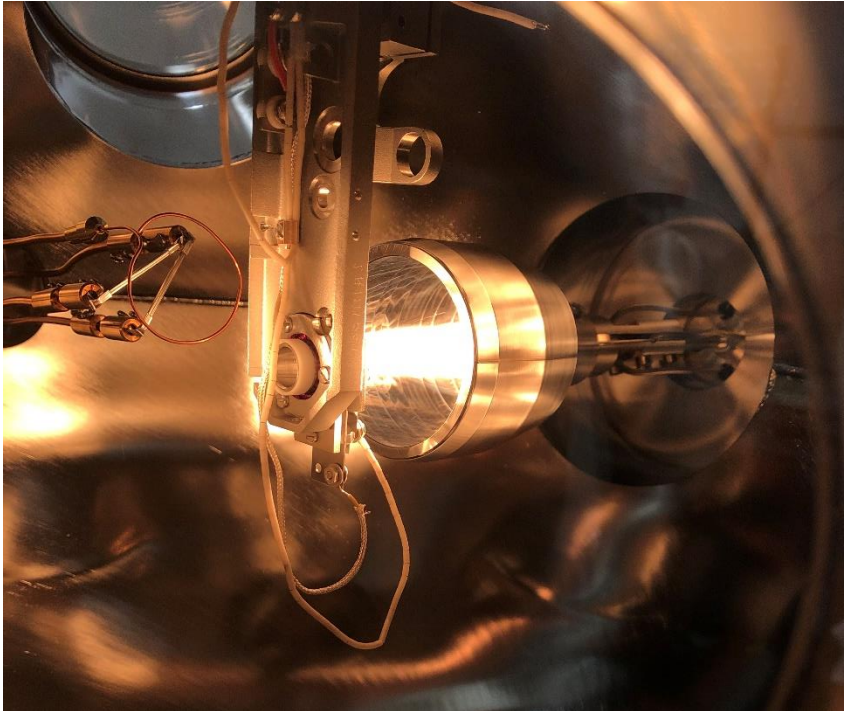
Outgassing of Cs-dispenser



- Current to Cs: from 2 to 4.3 A
- 4 h at 2.7 A
- Kept at 1 A during outgassing/heating with halogen lamp

GaN Photocathode Research

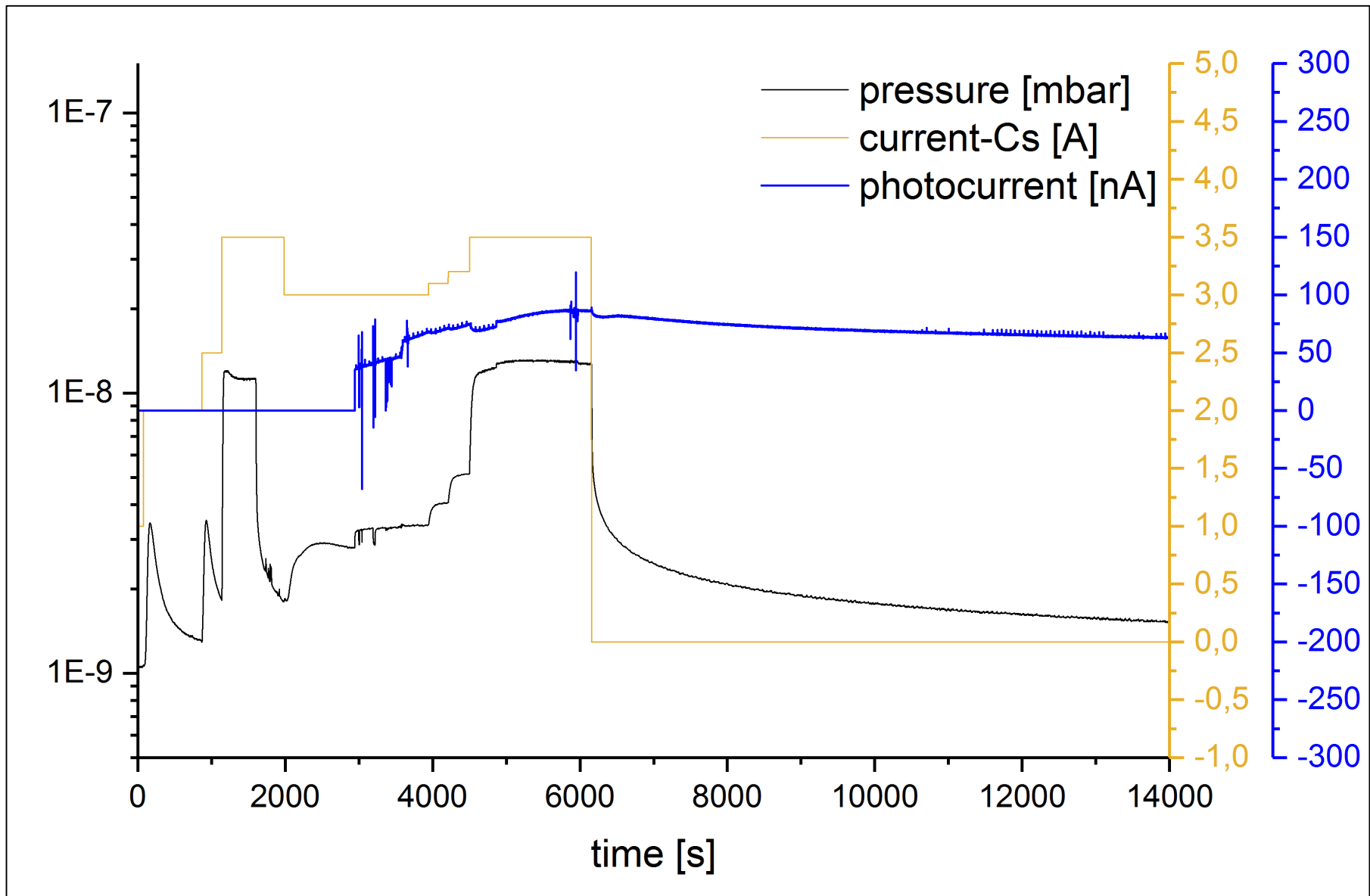
Outgassing of halogen lamp & heating sample



- Reached T on sample: 610°C
- Heating time: 15 min
- Stopped because of too bad vacuum ($\sim 1\text{E-}6\text{mbar}$)

GaN Photocathode Research

First activation- process

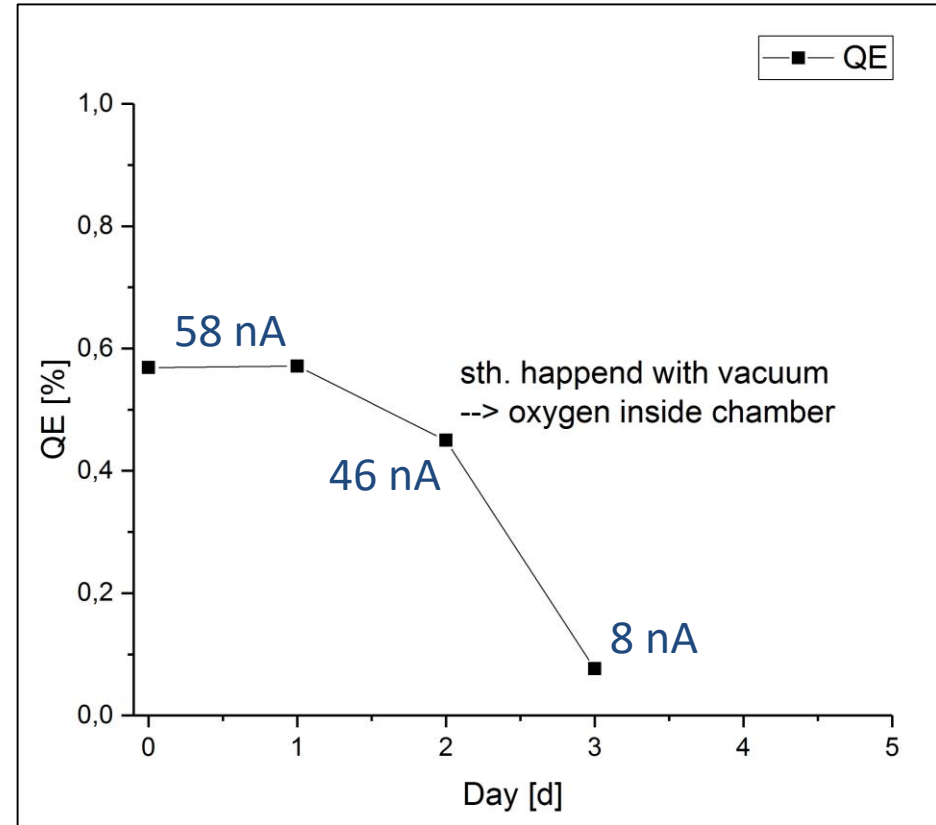


GaN Photocathode Research

First activation- QE

$$QE = \frac{N_{electrons}}{N_{photons}} = \frac{h \cdot c}{q_e} \cdot \frac{I}{\lambda \cdot P_{Light}(\lambda)}$$

- Planck-const. (h): 6.626E-34 J*s
- c: 2.9E9 m*s-1
- Elementary elect. charge (qe): 1.6E-19 C
- λ : 3.1E-7 m (310 nm)
- Power: 4E-5 W (40 μ W)

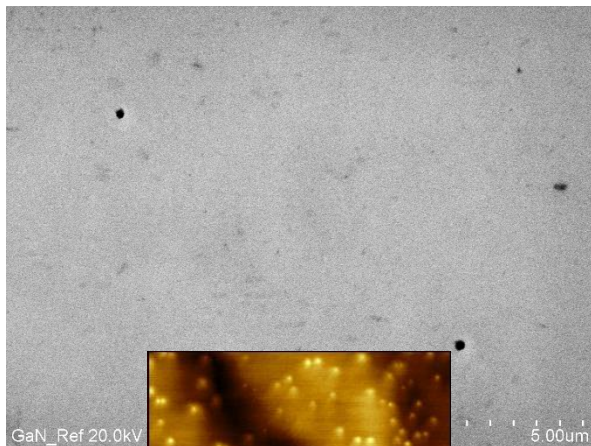


- reached ~0.58 %
→ no loss during the first hours
- On 2nd day after activation: oxygen in chamber
→ destroyed cathode

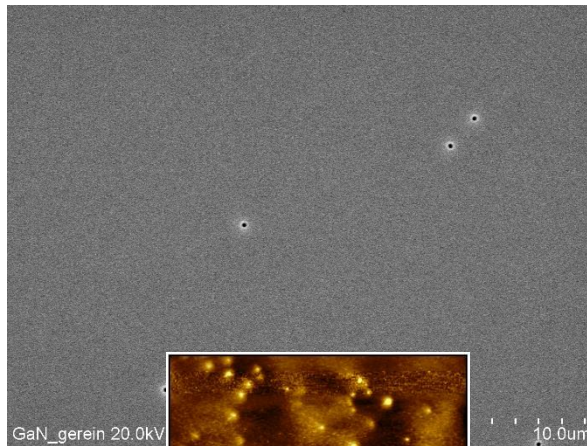
GaN Photocathode Research

Cleaning of GaN on sapphire

GaN: reference

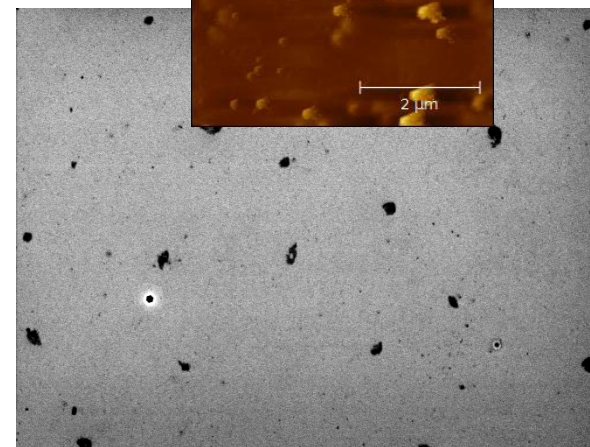
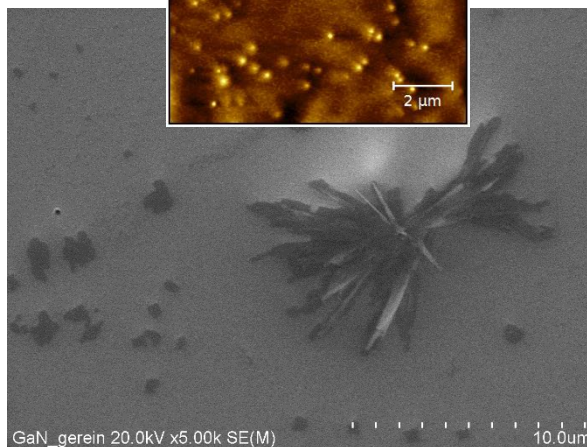
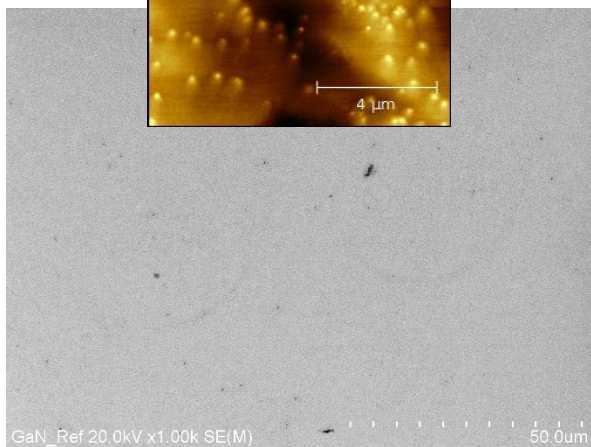
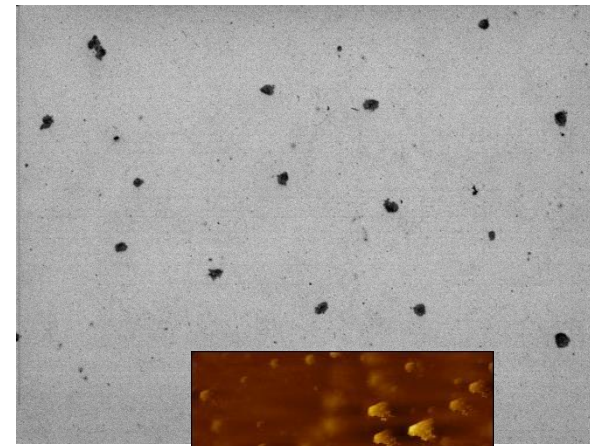


GaN: piranha+ 0.5 HF



↓ after ↓

GaN: piranha/ water, after 4h on air



Crystal growth after cleaning !?!?

→ Avoid air exposure+ use Glovebox & sealed bags

Conclusion

- Characterization and comparison of commercial available GaN wafer
 - GaN on sapphire, Si, SiC (different substrates)
 - AFM, XPS, EDX, SEM, RBS
- Connection from activation chamber to XPS chamber → 1st quarter 2020
- Activation of GaN wafer with Cs and characterization of activated GaN
 - further activations and improvement
- Comparison to GaAs & selfmade GaN (Uni Siegen)
- If successfully: test in SRF Gun II as a photocathode for high brightness beam

Thank you for your attention!

Thanks to the ELBE team

J. Teichert, A. Arnold, P. Zwartek, P. Lu, S. Ma, P. Murcek, H. Vennekate, R. Xiang, P. Evtushenko, M. Freitag, M. Justus, M. Kuntzsch, U. Lehnert, P. Michel, A. Ryzhov, C. Schneider, R. Steinbrück, K. Zenker,

and our co-workers

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I. Will MBI, Berlin, Germany

T. Kamps, J. Kühn, M. Schenck, M. Schmeißer, G. Klemz,

J. Voelker, HZB, Berlin, Germany

J. Sekutowicz, E. Vogel, F. Stephan, H. Qian, DESY, Germany

K. Aulenbacher, JGU, Mainz, Germany

M. Vogel, M. Schuhmacher, X. Jiang, Uni Siegen, Germany

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U. van Rienen, E. T. Tulu, Uni Rostock, Germany

